

**ASSEMBLY COMPRISING A PLURALITY OF MASK CONTAINERS,  
MANUFACTURING SYSTEM FOR MANUFACTURING SEMICONDUCTOR  
DEVICES, AND METHOD**

5

Abstract of the Disclosure

10 The present invention relates to a system for the  
manufacture of semiconductor devices by lithography, and  
in particular to an assembly of mask containers for use in  
such a system. The system comprises: a plurality of mask  
containers adapted to engage with one another such that  
two or more containers can be carried together as a stack;  
a plurality of lithography bays; a transport rail system  
for carrying the containers between different lithography  
15 bays. Each lithography bay has a transmitter/receiver  
unit for communicating lithography data with a tracking  
device located in each container, allowing for more  
efficient mask management. The transportation of the  
containers in stacks results in an improvement in  
20 efficiency.